

In re Application of

Ryo TAKAI et al.

Appln. No.: 10/073,593

Filed: February 12, 2002

For: EXPOSURE APPARATUS INCLUDING
INTERFEROMETER SYSTEM

Docket No. 00862.022516

Examiner: M. Lyons

Group Art Unit: 2877

Date: October 16, 2003

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Transmitted herewith is an Amendment and a Request for Approval of Drawings Changed in the above-identified application.

☐ No additional fee is required.

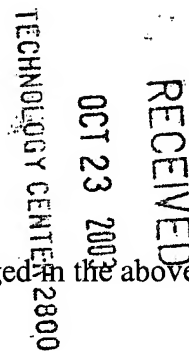
The fee has been calculated as shown below:

CLAIMS AS AMENDED						
	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NO. PREVIOUSLY PAID FOR	PRESENT EXTRA	RATE	ADDITIONAL FEE
TOTAL CLAIMS	37	MINUS	25	12	x \$ 9 \$18	\$ 216.00
INDEP. CLAIMS	7	MINUS	5	2	x \$43 \$86	\$ 172.00
Fee for Multiple Dependent claims \$145/\$290						
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT---						\$ 388.00

☐ °Verified Statement claiming small entity status is enclosed, if not filed previously.

☒ A check in the amount of \$388.00 is enclosed.

☐ Charge \$___ to Deposit Account No. 06-1205. A duplicate of this sheet is enclosed.



2877
\$

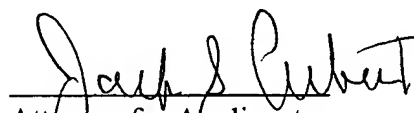
☒ Any prior general authorization to charge an issue fee under 37 C.F.R. § 1.18 to Deposit Account No. 06-1205 is hereby revoked. The Commissioner is hereby authorized to charge any additional fees under 37 C.F.R. §§ 1.16 and 1.17 which may be required during the entire pendency of this application, or to credit any overpayment, to Deposit Account No. 06-1205. A duplicate of this paper is enclosed.

☐ A check in the amount of \$_____ to cover the Extension fee for response within _____ months is enclosed.

☐ A check in the amount of \$_____ to cover the Information Disclosure Statement fee is enclosed.

☒ Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our address given below.

Respectfully submitted,



Attorney for Applicants

Jack S. Cubert

Registration No. 24,245

FITZPATRICK, CELLA, HARPER & SCINTO
30 Rockefeller Plaza
New York, New York 10112-3801
Facsimile: (212) 218-2200

JSC/vlp

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00862.022516.

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Ryo TAKAI et al.

Application No.: 10/073,593

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For: EXPOSURE APPARATUS INCLUDING
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)
: Examiner: M. Lyons
)
: Group Art Unit: 2877
)
: Confirmation No. 4328
)
:
) October 16, 2003
:

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Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Sir:

In response to the Official Action dated July 16, 2003, please amend the above-identified application as follows:

10/21/2003 ZJUHR1 00000117 10073593

01 FC:1202
02 FC:1201

216.00 OP
172.00 OP